



IPW

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hisaji OYAKE et al.

Group Art Unit: 2854

Application No.: 10/500,816

Examiner: A. NGUYEN

Filed: July 7, 2004

Docket No.: 120321

For: METHOD OF MANUFACTURING STAMPER FOR MANUFACTURING  
INFORMATION MEDIUM, STAMPER, AND PHOTORESIST MASTER

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

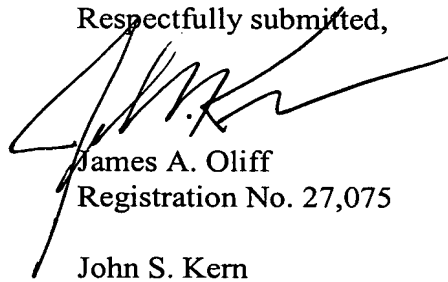
Sir:

In reply to the October 17, 2005 Restriction Requirement, Applicants provisionally elect Group I, claims 1-5, with traverse.

It is also respectfully submitted that the subject matter of all claims 1-9 is sufficiently related that a thorough search for the subject matter of any one Group of claims would encompass a search for the subject matter of the remaining claims. Thus, it is respectfully submitted that the search and examination of the entire application could be made without serious burden. See MPEP §803 in which it is stated that "if the search and examination of an entire application can be made without serious burden, the examiner must examine it on the merits, even though it includes claims to independent or distinct inventions" (emphasis added). It is respectfully submitted that this policy should apply in the present application in order to avoid unnecessary delay and expense to Applicants and duplicative examination by the Patent Office.

Thus, withdrawal of the Restriction Requirement is respectfully requested.

Respectfully submitted,



James A. Oliff  
Registration No. 27,075

John S. Kern  
Registration No. 42,719

JAO:JSK/jfb

Date: November 17, 2005

**OLIFF & BERRIDGE, PLC**  
**P.O. Box 19928**  
**Alexandria, Virginia 22320**  
**Telephone: (703) 836-6400**

**DEPOSIT ACCOUNT USE  
AUTHORIZATION**

Please grant any extension  
necessary for entry;  
Charge any fee due to our  
Deposit Account No. 15-0461